

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 9134**
Shoriki NARITA et al. : Docket No. 2001_1718A
Serial No. 09/988,704 : Group Art Unit 2625
Filed November 20, 2001 : Examiner Sheela Chawan

METHOD AND APPARATUS FOR
CORRECTING INCLINATION OF IC ON
SEMICONDUCTOR WAFER

AMENDMENT

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the Office Action dated December 29, 2004, the period for response to which having been extended by one-month to April 29, 2005, please amend the above-identified application as follows.